

WHAT IS CLAIMED IS:

1. A method of fabricating a micromechanical device, the method comprising:
forming at least two micromechanical devices on a common substrate;
applying a liquid overcoat material to said micromechanical devices;
separating said common substrate to separate said devices; and
removing said overcoat from said micromechanical devices.
2. The method of Claim 1, said applying a liquid overcoat material comprising:
immersing said common substrate in a liquid overcoat material;
3. The method of Claim 1, said applying a liquid overcoat material comprising:
applying said liquid overcoat material to said common substrate; and
spinning said common substrate to disperse said liquid overcoat material.
4. The method of Claim 1, said applying a liquid overcoat material comprising:
spraying said liquid overcoat material onto said common substrate.
5. The method of Claim 1, said applying a liquid overcoat material comprising:
spraying said liquid overcoat material onto said common substrate using a low pressure spray.
6. The method of Claim 1, said applying a liquid overcoat material comprising:
spraying said liquid overcoat material onto said common substrate using a high pressure spray.
7. The method of Claim 1, said applying a liquid overcoat material comprising:
spraying said liquid overcoat material onto said common substrate using a low pressure pneumatic spray.
8. The method of Claim 1, said applying a liquid overcoat material comprising:

spraying said liquid overcoat material onto said common substrate using a high pressure pneumatic spray.

9. The method of Claim 1, said applying a liquid overcoat material comprising:
 - nebulizing said liquid overcoat material using Meinhard nebulization; and
 - spraying said nebulized liquid overcoat material onto said common substrate.
10. The method of Claim 1, said applying a liquid overcoat material comprising:
 - nebulizing said liquid overcoat material using ultrasonic nebulization; and
 - spraying said nebulized liquid overcoat material onto said common substrate.
11. The method of Claim 1, said applying a liquid overcoat material comprising:
 - dispensing droplets of said liquid overcoat material from a nozzle using a heated droplet dispenser; and
 - depositing said droplets onto said common substrate.
12. The method of Claim 1, comprising:
 - curing said liquid overcoat material.
13. The method of Claim 1, comprising:
 - curing said liquid overcoat material by heating said liquid overcoat material.
14. The method of Claim 1, comprising:
 - curing said liquid overcoat material using ultraviolet light.
15. The method of Claim 1, said applying a liquid overcoat material to said micromechanical devices comprising:
 - applying a urethane acrylate resin.
16. The method of Claim 1, said applying a liquid overcoat material to said micromechanical devices comprising:

applying an epoxy acrylate resin.

17. The method of Claim 1, said applying a liquid overcoat material to said micromechanical devices comprising:

applying an acrylate monomer.

18. The method of Claim 1, said removing said overcoat from said micromechanical devices comprising:

removing said overcoat using an isotropic etch.

19. A method of fabricating a micromechanical device, the method comprising:

forming at least two micromechanical devices on a common substrate;

immersing said common substrate in a liquid overcoat material to coat said micromechanical devices;

separating said common substrate to separate said devices; and

removing said overcoat from said micromechanical devices.

20. The method of Claim 19, comprising:

spinning said common substrate to disperse said liquid overcoat material.

21. The method of Claim 19, comprising:

curing said liquid overcoat material.

22. The method of Claim 19, said applying a liquid overcoat material to said micromechanical devices comprising:

applying a urethane acrylate resin.

23. The method of Claim 19, said applying a liquid overcoat material to said micromechanical devices comprising:

applying an epoxy acrylate resin.

24. The method of Claim 19, said applying a liquid overcoat material to said micromechanical devices comprising:
applying an acrylate monomer.
25. The method of Claim 19, said removing said overcoat from said micromechanical devices comprising:
removing said overcoat using an isotropic etch.
26. A method of fabricating a micromechanical device, the method comprising:
forming at least two micromechanical devices on a common substrate;
spraying a liquid overcoat material onto said common substrate to coat said micromechanical devices;
separating said common substrate to separate said devices; and
removing said overcoat from said micromechanical devices.
27. The method of Claim 26, comprising:
curing said liquid overcoat material.
28. The method of Claim 26, said applying a liquid overcoat material to said micromechanical devices comprising:
applying a urethane acrylate resin.
29. The method of Claim 26, said applying a liquid overcoat material to said micromechanical devices comprising:
applying an epoxy acrylate resin.
30. The method of Claim 26, said applying a liquid overcoat material to said micromechanical devices comprising:
applying an acrylate monomer.

31. The method of Claim 26, said removing said overcoat from said micromechanical devices comprising:
- removing said overcoat using an isotropic etch.
32. A method of fabricating a micromechanical device, the method comprising:
- forming at least two micromechanical devices on a common substrate;
 - nebulizing a liquid overcoat material;
 - spraying said nebulized liquid overcoat material onto said common substrate to coat said micromechanical devices;
 - separating said common substrate to separate said devices; and
 - removing said overcoat from said micromechanical devices.
33. The method of Claim 32, said nebulizing said liquid overcoat material comprising:
- nebulizing said liquid overcoat material using Meinhard nebulization.
34. The method of Claim 32, said nebulizing said liquid overcoat material comprising:
- nebulizing said liquid overcoat material using ultrasonic nebulization.
35. The method of Claim 32, comprising:
- curing said liquid overcoat material.
36. The method of Claim 32, said applying a liquid overcoat material to said micromechanical devices comprising:
- applying a urethane acrylate resin.
37. The method of Claim 32, said applying a liquid overcoat material to said micromechanical devices comprising:
- applying an epoxy acrylate resin.

38. The method of Claim 32, said applying a liquid overcoat material to said micromechanical devices comprising:
- applying an acrylate monomer.
39. The method of Claim 32, said removing said overcoat from said micromechanical devices comprising:
- removing said overcoat using an isotropic etch.
40. A method of fabricating a micromechanical device, the method comprising:
- forming at least two micromechanical devices on a common substrate;
 - dispensing droplets of a liquid overcoat material from a nozzle using a heated droplet dispenser;
 - depositing said droplets onto said common substrate to coat said micromechanical devices;
 - separating said common substrate to separate said devices; and
 - removing said overcoat from said micromechanical devices.
41. The method of Claim 40, comprising:
- curing said liquid overcoat material.
42. The method of Claim 40, said applying a liquid overcoat material to said micromechanical devices comprising:
- applying a urethane acrylate resin.
43. The method of Claim 40, said applying a liquid overcoat material to said micromechanical devices comprising:
- applying an epoxy acrylate resin.

44. The method of Claim 40, said applying a liquid overcoat material to said micromechanical devices comprising:
- applying an acrylate monomer.
45. The method of Claim 40, said removing said overcoat from said micromechanical devices comprising:
- removing said overcoat using an isotropic etch.